DECLARATION

The information provided is true to the best of my knowledge. If selected, I agree to abide by the rules and regulations of the programme and shall attend the programme for the entire duration. I also undertake the responsibility to inform the convener, in case I am unable to attend the programme.

Signature of the Applicant

SPONSORSHIP CERTIFICATE

Dr/Mr/Ms.

is an employee of our Institute/Organization and is hereby sponsored to participate in the FDP programme on "Advancements in MEMS & NEMS Technologies" during 19-21 November, 2015 conducted by Department of Mechanical Engineering, Gokaraju Rangaraju Institute of Engineering and Technology, Bachupally, Hyderabad 500 090.

Place:

Date:

Signature of Head of Institution
(With seal)

IMPORTANT DATES

Last Date for Registration 16-11-2015

Registration fee

- The Registration fee for Faculty/Industry people is Rs. 500
- DD Can be drawn in favor of M/S HOD MECHANICAL DEPARTMENT Payable at Hyderabad
- The registration fee includes Course Material, Lunch, and Snacks
- Applications can be downloaded or photocopied.
- Selection is based on first come first serve basis.
- Participation Certificates will be provided to each participant.

ADVISORY COMMITTEE

Chief Patrons

Dr. G V K Ganga Raju-President, GRES Sri. G V K Ranga Raju-Vice-President, GRES

Patrons

Prof. P.S. Raju Director, GRIET
Dr. Jandhyala N Murthy Principal, GRIET
Sri. B.Ch. Nookaraju HOD, Mech. Engg.

Program Conveners

Dr. N. Sateesh Professor
Dr. R. Raman Goud Professor

Organising Committee

Dr. Swadesh Kumar Singh Professor
Dr. L Jayahari Professor
Dr. Karthikeyan Professor

Sri D.S.Nagaraju. Associate Professor Dr.Ramasubbaiah Associate Professor Dr.K.Satyanarayana Assistant Professor Sri.K.Prashanth Reddy Assistant Professor

Communication Address

Sri. B.Ch.Nookaraju

Head, Department of Mech. Engg.

GOKARAJU RANGARAJU

Institute Of Engineering and Technology

(Autonomous)

Bachupally, Kukatapally, Hyderabad-500090. **Email:** nookaraju@griet.ac.in, sateesh.nagari1@gmail.com

Mobile: 8985215775,9553345092





Faculty Development Program

ON

"Advancements in MEMS & NEMS

Technologies"

(19-21 November, 2015)

UNDER TEQIP II



Organized By
Department of Mechanical Engineering

GOKARAJU RANGARAJU
INSTITUTE OF ENGINEERING AND TECHNOLOGY

(Autonomous)
Accredited by NBA, NAAC with 'A' Grade

Bachupally, Kukatapally, Hyderabad-500 090 Web: www.griet.ac.in

About the GRIET

GRIET was established in the year 1997 with a panoramic vision to dynamise all round pivotal progress. Highly qualified and widely experienced faculty are the strong substratum to substantiate the avowed objectives of the institute. Our aim focusses on the concept of an integrated learning environment to enrich the student's potential and satisfy competitive industry and harmonious society. The unique selling proposition of the institute is the teaching-learning which emphasizes on practical skills and social relevance.

About the Department

Started in 1997, the department of Mechanical Engineering has been striving to impart quality education to the students. The department has well equipped laboratories and highly qualified staff. The department offers one B.Tech (Mech), M.Tech. (DFM), M.Tech (Thermal) programmes with an intake of 120 and 18 students each in PG respectively. The staff and students are engaged in advance research in the area of Metal Forming/Manufacturing/CAD/CAM sponsored by AICTE and DST. The Mechanical Engineering Department is recognized as a research centre by JNTUH, Hyderabad. The B.Tech. (Mechanical) is accredited by NBA in 2014-15 for two years.

Course Overview

Micro-Electro-Mechanical Systems (MEMS) and its Nanoscale counterpart, Nano-Electro-Mechanical Systems (NEMS) deal with the entire technology of design, fabrication, and deployment of micro and Nano-scale Mechanical Engineering components unified with the required electronics for sensing and actuation applications . Such devices find immense applications in the fields of Defence, Medical, Automotive, Communication and Aerospace. These components are crucial for data acquisition in research. These include precision sensors, integrated mechanical filters and switches, accelerometers, gyroscopes and inkjet printers.

Course Contents

- Fundamental basis of MEMS/NEMS.
- Overview of basic Microfabrication processes.
- Bulk and Surface Micromachining.
- Polymer and Carbon MEMS.
- MEMS design, Modeling and Simulation.
- MEMS-based Sensors and Actuators.

Resource Persons

Invited talks are given by eminent professors from IIT Hyderabad on various aspects of the Advancements in MEMS and NEMS Technologies and related issues.

- 1. Dr. Ashok Kumar Pandey-Assistant Professor, Department of Mechanical and Aerospace Engineering.
- 2. Dr. Shiv Govind Singh-Associate Professor, Department of Electrical Engineering.
- 3. Dr. Prem Pal Associate Professor, Department of Physics.
- 4. Dr. Chandra Shekhar Sharma, Asst. Professor, Department of Chemical Engineering.
- 5. Industry experts

Eligibility

- Faculty Members from Engineering/PG Colleges.
- Technical staff from institute/ industry
- Resource Persons From Industry



Faculty Development Program On "Advancements in MEMS and NEMS Technologies" (19-21 November, 2015) (Under TEQIP Phase II) Registration Form

2. Designation	n :	
3. Applicant's Status: Faculty /Technical staff/ Industry perso		
I. Institution	:	
5. Whether the institution has AICTE Recognition: (Yes/No)		
5. Educational Qualifications:		
7. Subjects Handled for last three years		
3. Experience:		_ Years
	Teaching:	
	Research:	
	Industry:	
9. D.D.Particulars:		

1. Name

10. Amount in Rs:

11. Any other information

12. Address for Correspondence with Email id:

DD No:

FOR MORE DETAILS

Sri. B.Ch.Nookaraju

Head Department of Mech. Engg.



Bank Name:

Signature of the applicant